

<b>Notice of References Cited</b>	Application/Control No. 10/608,914	Applicant(s)/Patent Under Reexamination AGRAWAL, AVNEESH	
	Examiner Emmanuel Bayard	Art Unit 2638	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,075,990	06-2000	Shin, Yeong-Jong	455/440
*	B	US-6,377,801	04-2002	Kolev et al.	455/428
*	C	US-6,882,677	04-2005	Dehner et al.	375/132
*	D	US-6,657,985	12-2003	Park, Su-Won	370/342
*	E	US-5,506,863	04-1996	Meidan et al.	375/134
*	F	US-2004/0161018	08-2004	Maric, Svetislav	375/136
*	G	US-2004/0258136	12-2004	Liu et al.	375/133
*	H	US-6,658,044	12-2003	Cho et al.	375/135
*	I	US-6,031,864	02-2000	Bauchot et al.	375/133
*	J	US-6,264,713	07-2001	Lewis, II, Earl K.	55/481
*	K	US-5,907,545	05-1999	Arai et al.	370/342
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.